



Attorney Docket No.: 033082M194  
U.S. Serial No.: 10/775,145

**In the Specification:**

Please amend the paragraph at page 13, line 28 through page 14, line 12 as set forth below:

In the ~~top~~ lowermost box 78, the high-frequency electric power source 86 has an RF oscillator 106, an RF amplifier 108, a circulator 110 and a filter 112. The RF oscillator 106 generates a high-frequency signal defining a frequency (100 MHz) of the high-frequency electric power for generating the plasma. The RF amplifier 108 has a switching device consisting of, for example, FET, and generates high-frequency electric power of 100 MHz by amplification operation of the high-frequency signal from the RF oscillator 106 when direct-current power is applied from the direct-current power source 36 (Fig. 1) via the direct-current transmission cable 38 of, for example, 5 m to 20 m. The circulator 110 functions as an isolating circuit, that is, allows the high-frequency electric power (forward wave) from the RF amplifier 108 to pass therethrough with no substantial attenuation, but causes reflected waves from the matching unit 80 to flow in a dummy load resistance 114 to absorb them. The filter 112 selectively allows the high-frequency electric power from the circulator 110 to pass therethrough but shuts off or removes frequency components above the transmission frequency (100 MHz).